



500.41374CX2

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): S. KANNO, et al
Serial No.: 10/658,281
Filed: September 10, 2003
For: WAFER STAGE FOR PROCESSING APPARATUS AND
WAFER PROCESSING METHOD
Group: 3742
Examiner: S. Fuqua

AMENDMENT

Mail Stop: Amendment (Fee)
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

July 12, 2005

Sir:

The following amendments and remarks are respectfully submitted in connection with the above-identified application in response to the Office Action dated January 12, 2005, as listed below and as set forth on the following pages:

Amendment of the Claims; and

Remarks are included following the amendments.